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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: :
MAIK WIEMER et al. :
Serial No. :
Filed: :
For: METHOD FOR PRODUCING A :
TORSION SPRING :

INFORMATION DISCLOSURE STATEMENT

Hon. Commissioner of Patents
and Trademarks
Washington, D.C. 20231

Sir:

In accordance with the duty to disclose information material to the examination of this application as set forth in 37 CFR 1.56, copies of the following publications are submitted herewith:

(1) Article: C. Kaufman et al., "Characterization of Material and Structure Defects on Micromechanical Scanners by Means of Frequency Analysis," Proceedings of Micro Materials, (1995), P443 ff;

(2) Article: J. Choi et al., "Silicon Angular Rate Sensor by Deep Reactive Ion Etching," Proceedings of the International Symposium on Microsystems, Intelligent Materials and Robots (Sendai, Japan, 1995), pgs. 29 through 32;

(3) German patent publication DE 28 18 106 (12/7/78);

(4) P. Enoksson et al., "A Silicon Resonant Sensor Structure for Coriolis Mass-Flow Measurements", Journal of

.....Page 2

Micromechanical Systems, Vol. 6, No. 2 (June 1997), pgs. 119
through 125;

(5) International patent application WO 96/38710
(12/5/96); and

(6) German patent publication DE 41 26 100 (2/18/93).

Each of documents "1" through "5" was cited and its
relevance to the claimed invention discussed within the body of
International patent application PCT/EP 00/06957 filed July 20,
2000. The present application is the United States national
stage of such application.

In addition, documents 3 and 5, along with document
"6" were cited in the International Search Report issued November
21, 2000 in International patent application PCT/EP 00/06957.
filed June 6, 2000. As set forth in the Search Report, each of

such references was cited as category "A" ("document defining the general state of the art which is not considered to be of particular relevance").

Respectfully submitted,



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**Form PTO-1449
(REV. 2-83)**

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

APPLICANT

MAIK WIEMER et al.

FILING DATE

GROUP

U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

			C. Kaufman et al., "Characterization of Material and Structure Defects on Micromechanical Scanners by Means of Frequency Analysis," <u>Proceedings of Micro Materials</u> (1995), pg. 443 ff
			P. Enoksson et al., "A Silicon Resonant Sensor Structure for Coriolis Mass-Flow Measurements," <u>Journal of Micromechanical Systems</u> , Vol. 6, No. 2, (June 1997), pgs. 119 through 125
			J. Choi et al., "Silicon Angular Rate Sensor by Deep Reactive Ion Etching," <u>Proceedings of the International Symposium on Microsystems, Intelligent Materials and Robots</u> (Sendai, Japan, 1995), pgs. 29 through 32

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.